

1 1 ,
2 1 ,
3 2 - ,
4a 4h 1 ,
5 2 ,
6 5 - ,
7 3 ,
8 7 - ,
9a 9j 4 ,
10 ,
11 5 ,
12 11 ,
13 12 A - B ,
14a 14h 11 ,
15 6 ,
16 7 .
< >
10 - - , 11 - - ,
12 - - , 13 - - (),
14 - - , 15 - - ,
16 - - , 16S - - ,
16D - - , 17 - - (),
18 - - , 19 - - ,

20 - - , 21 - - (contact hole),

22 - - , 23 - - ,

23a - - 凸 , 23b - - 凹 ,

23c - - 凸 , 23d - - 凹 ,

23e - - 凹 , 23f - - 凸 ,

23g - - , 23h - - ,

24 - - (TFT), 25 - - ,

26 - - , 26a - - 凸 ,

26b - - 凹 , 26c - - 凸 ,

26d - - 凹 , 29 - - ,

30 - - , 31 - - (),

32 - - , 33 - - ,

34 - - , 36 - - (),

37 - - , 38 - - ,

39 - - (), 40 - - ,

41 - - ,

42 - - (backlight unit), 50 - - ,

63 - - , 63a - - 凸 ,

63b - - 凹 , 67 - - ,

67a - - 凸 , 67b - - 凹 ,

d - - 凸 , H - - 凸 ,

PX - - ,

H1 - - 1 (凸 (23a) 凹 (23b)),

H2 - - 2 (凸 (23c) 凹 (23d)),

D1 - - 凹 (26b) , D2 - - 凸 (26c) ,

i - - .

가

(back light unit)

가

가

10

(起伏)

(主散亂部)
凸
(高低差)가

(H) 0.6~1.2 μ m
10 μ m
(contrast)

凸

(d) 3~20 μ m

1 μ m

(配向)

0.5 μ m

가

가

가

1

1 2

(緩斜面)

1 2

1

1 2

6) (17) SiOx(silicon oxide) CVD 100nm 150nm (13) (1)

(18) (15) Ta(), Cr(), Al(), Mo(), W() Cu() (17) 200nm 400nm (18)

(mask) PH₃/H₂ (dop ing) (16) 5 × 10¹⁵ atoms/cm² (dose) (16) 80keV 가 (annealing) (24)

4a SiOx 500nm 700nm (32) , PECVD(Plasma Enhanced Chemical Vapor Deposition) (18), (15) (17) (32) (16) (21, 22)

4b , Ta, Cr, Al, Mo, W, Cu 500nm 700nm (32) (19), (33) (14),

4c (25) SiNx(Silicon Nitride) PECVD (29) (25) (3)

4d (spin coat) (26) (positive) (感光性) (25) 1μm 4μm (10) (14) 2 (pre - bake) (15) (PX) 凸 (26a) 凹 (26b) 1 (26) 0.1μm 0.5μm 가 (15) (14) (26) (PX) 凸 (26a) 凹 (26b) (D1) 20μm 400μm

4e (26) 1 (photomask) (29) (33) (30) (26) (i) 200mJ 1000mJ (26) (PX) (14) (15) (D1) 2μm 20μm , 10mJ 200mJ 凹凸 (26b) (26) (34) 가

4f (26) 凸 (26) 凹 (26d') (30) (26) , 2 (34) 10 200mJ , 凹 (26d') (26) (25)

4g (26d')가 (成型用) . 凸 (26c) (10) 가 가 , 凸 (26c) (26) 凸 (26c') 凹 (26d) 2 凹 (26b) (D1)

4h (26) , Al, Ni, Cr Ag (sputter) 100nm (23) .

(11) (37) (37) (36) . (38) , (36) ITO(Indium Tin Oxide)

(10) (11) (31, 39) (26) (31) (cure) (rubbing) (39) (38)

(10) (11) , (31, 39) (12) (10) (11) (nematic) (40) (37) (36)

5 (H2) 2 (23a) 凸 (23a) (23) 1 凹 (23b) (PX) 2 凸 (23c) , 凸 (23c) 凹 (23d) (PX) (H1) 1 凸

, 1 (PX) (PX) . , 2 (PX) , (, (PX)

. 1 2 H2 , 2 . ,

1 , 2 (23) , (26) 2 (23) (23) (short) (26) (点缺陷) (15) (15) (23) (14) (23) , (crosstalk)

1, 2, 5, 6, 5, 1, 가

(32), 5, (50), (25), (23), (26), (25)

, 1, (32), (50), (26), (23)

, 1, (23), 6, (23), 6

2, 1, 가, 가, 가

, 3, 8, 7, 7, 8, 1, 가

5), (23), 가, 1, (15), (32), (25), (26), (26), (1)

, 1, (23), 8, (23), 1, (15), (23)

3, 1, 가, (15), (23), (15)

, 4, 1, 9, 가, 9

(10) CVD, 50nm, (13), (13), (16),

(13), (17) SiOx, CVD, 100nm, 150nm, (16)

(18) (15) Ta, Cr, Al, Mo, W Cu
 (17) 200nm 400nm
 (16) PH₃/H₂ 가 80keV 가 , 5 x
 10¹⁵ atoms/cm² (16)
 (24)

(10) 9a 9d 9a 9d
 4a 4d 가 , 0.1μm 0.5μm 가
 (15) (14) (26) (PX)
 , 凸 (26a)가 , 凸 (26a) 凹 (26b)가
 , 凹 (26b) (D1) 20μm 400μm

9e , (63) (26) 0.6μm
 , (10)

9f , (63) (PX) (14) (15)
 (透光部) (64)
 凹 (26b) (D1) 2μm 20μm , 50mJ 4000mJ
 가 (63) , 凹凸 凹凸 (64) , ,

9g 凹 (63b') (63) , 凸 (63a') (26)
 凹 (63b')

9h (63a')가 (10) 가 가 , (63) 凹 (63b') 凸
 凹 (63b) 凹 (63b) 凸 (63a)

9i 凹 (63b) 凸 (63a) (67) (63) 가
 凹 (67b) 凸 (67a) (67) 2 (26) 0.3μm , (10)
 凹 (67b) 2 2 凹 (67b)

9j Al, Ni, Cr Ag 100nm (67)
 , (23)

4 (23) , (H1)
 1 凸 (H2) 2 1 (PX)
 凸 (23a) 凸 (23a) 凹 (23b) 2 凹 (PX)
 凹 (23e) 凹 (23e) 凸 (23f) , 1
 (PX) , 2 (PX)
 , 2 (PX)

1 가

5

11 1 , 12

, 13 12 A - B

(10), (11), (10, 11) (12)
(11) (12)

, (10)

(10) (13), (23), (23)

(14), (23) (15),

(15) (14) (TFT;

24) (23) (31)

(11) (36) , (36) (37), (37)

(38) , (38) (39) , (40) (37)

(36)

(12) (23) (PX) (PX)

2 (15) 2 (14) (24) (15)

(23) (14) , (14) (12) (PX) 가 ,

(38) (PX)

(10) , TFT(24) (16) , (16)

(15) (18) , (18) (16)

(16S) (16D) (21, 22) (23)

(14) (19) (20)

(16) (13) , (13) (17)

(18) (17) (16) , (17) (17) (1)

5) (18) (15) (17) (32)

(21, 22) (18) (16) (16S) (16D)

(32) (17) (19) (20) (

21, 22) (16) (16S) (16D) (32)

(19) (32) (33) (20) (3

2) (14) (19), (33), (20) (1

4) (32) (25)

(25) (33) (29) (26)
 (26) (25) (29) (33)
 (30) (23) (29, 30) (33) (2)
 6) (31)

(26) (PX) 1
 (PX) 2
 (26b) (PX) 2 1
 2 (PX) 1
 (26c) (26d) (26a) (26a) (26c)

(23) (11) (12) (26)
 (23) (26) (PX) (PX)
 2 1

(23) (10) 가 (23g)

(23) 1 (26) (26b) (23b) (26) (2
 6a) (23a) 2 (26) (26c) (23a) (23b)
 3c) (26) (26d) (23d) 1 (23a) (23b)
 2
 (23b) 1 , H2가 (23c) H1 (23a)
 (23d) 2

14a 14h (10) (10)
 (13) TFT(24) (16) CVD
 50nm (13)

(17) SiOx CVD 100nm 150nm (16)
 (13)

(18) (15) Ta, Cr, Al, Mo, W Cu
 (17) 200nm 400nm
 (18)
 (16) PH₃/H₂ 가 80keV 가 5x
 10¹⁵ atoms/cm² (16)
 (24) (16S) (16D)

14a (18), (16), (15), (16S), (32), (17), (16D), PECVD, SiOx, 500nm, 700nm, (32), (21, 22)

14b (19), (20), (32), (20), (33), Ta, Cr, Al, Mo, W, Cu, 500nm, 700nm, (14),

14c (29), (25), SiNx, PECVD, (25), (32)

14d 1μm, 4μm, (26), (10), (14), 2, (15), (26), (26a), (26b), 1, (26), (26a), (26b), (D1), 20μm, 400μm, (26b), (15), 0.1μm, 0.5μm

14e (i) 200mJ, 1000mJ, (26), (33), (30), (29), (26), (26), (PX), (14), (15), (D1), 2μm, 20μm, (34), 10mJ, 200mJ, (26b), (26), (34), 가

14f 6c', 25), (26d'), (30), (26), (26), 2, (34), (26d'), (26), (26)

14g (26d')가, (26c), (D2), (10)가, 가, (26), (26c), (26c), (26d), (26c'), (26b), (D1), 2

14h (23), (23g), Al, Ni, Cr, Ag, 100nm, (23), (26)

(11), (37), (36), (38), (36), ITO, (37)

(10) (11) (31, 39) (31)
 (23) (26) , (38) ,
 (39) .

(10) (11) (31, 39)
 (12) (10) (11)
 (40) (12) (10) (11)
 (37) (36) .

1 (23)
 (H1) 1 (H2) 2 1 (PX)
 X) □ (23a) □ (23a) □ (23b) 2 □ (23d) (P
 □ (23c) , □ (23c) □ (23d)

1 (PX) (, 2 (PX) (,
 PX) (PX) .

1 2
 H2 , 2 , ,

5 , 2 (23) (26) 2 ,
 (23) (26)
 (23)
 , 2 (15) (14) , (15) (23)
 (14) (23)

6 .

15 가 , 15 , 5 가 5
 ,

TO , 15 (23) (23g) I
 □□ (26) , (23h) (23g)
 (23h) (26)

(12)

, 5 가 가 . ,

, 가 , 가 가

, 가 가 , ,

가 , ,

(57)

1.

1 2 , 1 2 1 2

1 2 ,

2 1 .

2.

1 , 1 가 ,
2 .

3.

2 , .

4.

1 , 1 .

5.

4 , 1 , 1 .

6.

4 , 1 , 가 .

7.

4 , 1 2 .

8.

7 , .

9.

7 , 1 1 2 2 .

10.

9 , 1 2 .

11.

7 , .

12.

11 , ,
1 .

13.

1 , 凸 .

14.

1 , 凹 .

15.

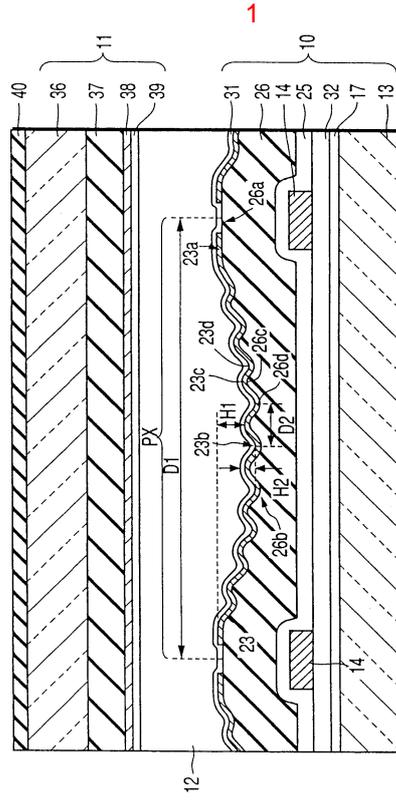
1 2 , 1 2 , 1 2 .

1 , 1 2 ,

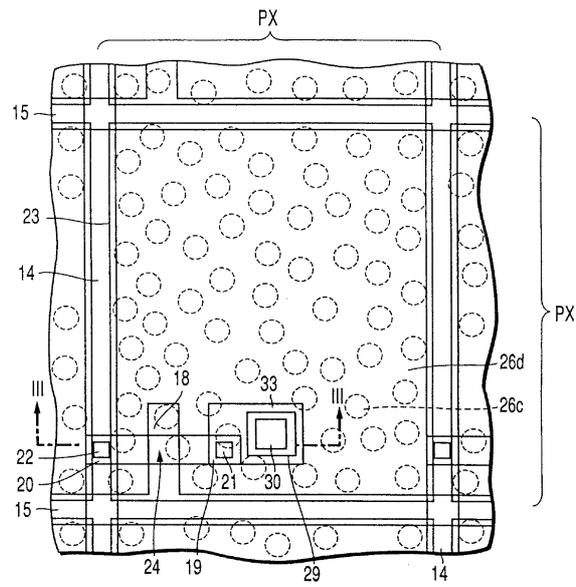
2 1 .

16.

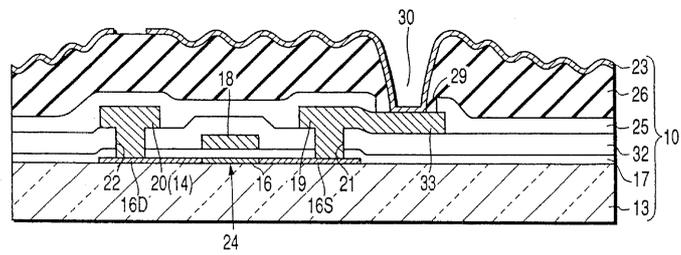
15 , .
17.
15 , 가 .
18.
17 , 凹凸 .
19.
18 , 1 2 .
20.
19 , .
21.
17 , .
22.
21 , , .



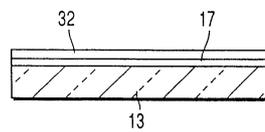
2



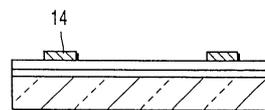
3



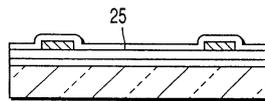
4a



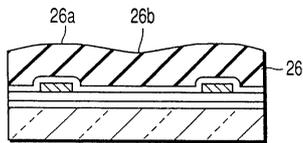
4b



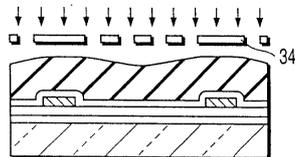
4c



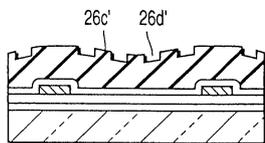
4d



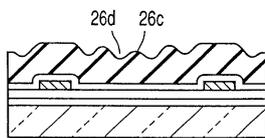
4e



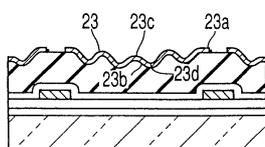
4f



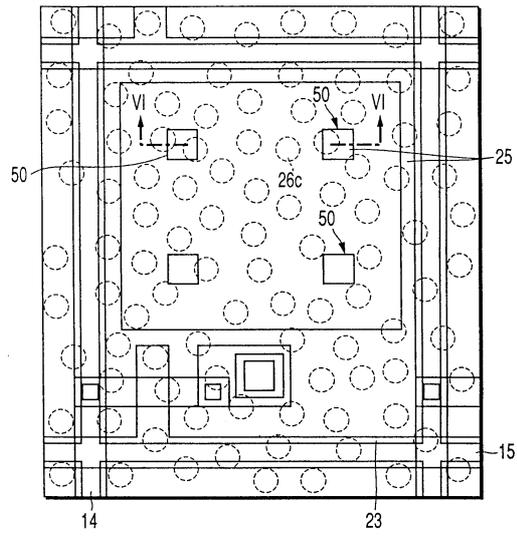
4g



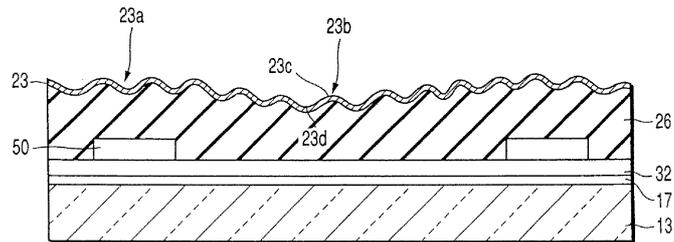
4h



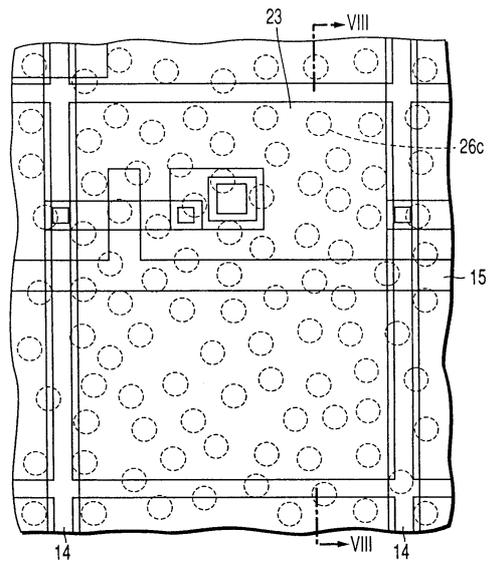
5



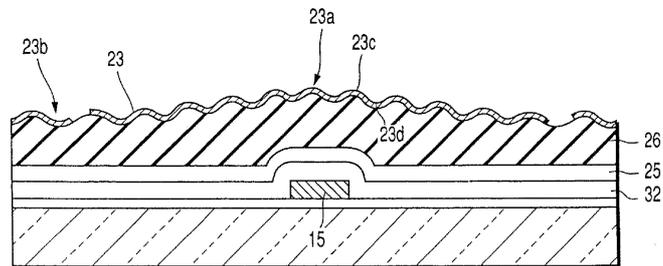
6



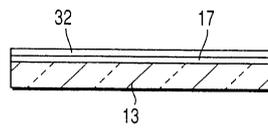
7



8



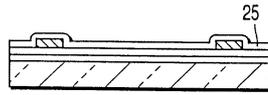
9a



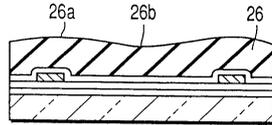
9b



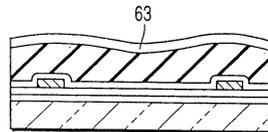
9c



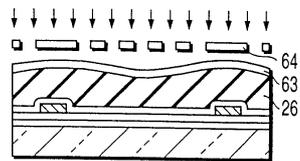
9d



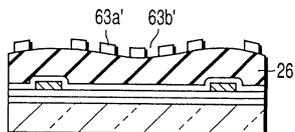
9e



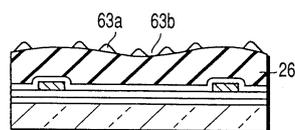
9f



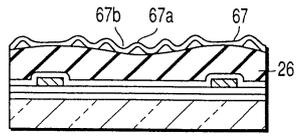
9g



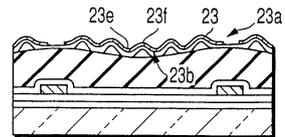
9h



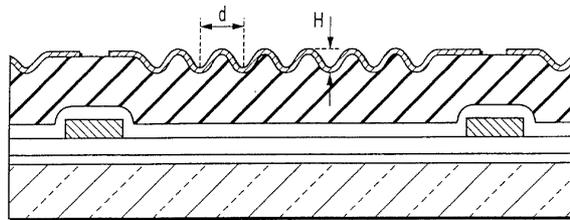
9i



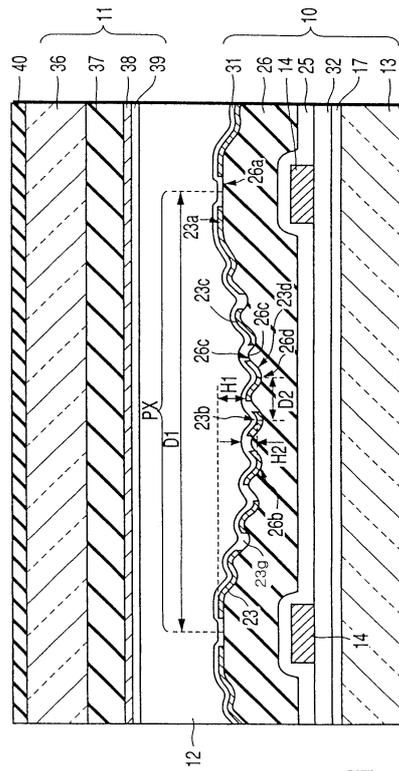
9j



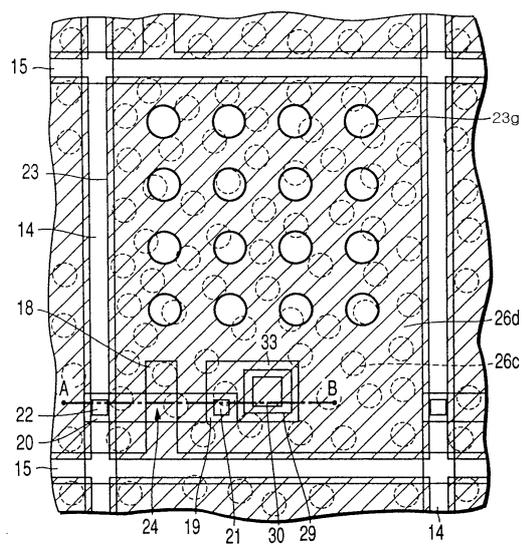
10



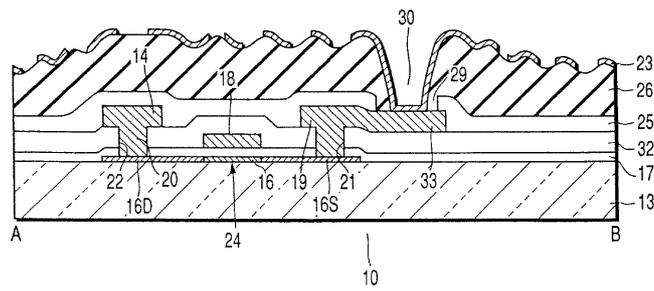
11



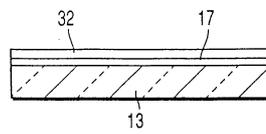
12



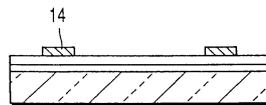
13



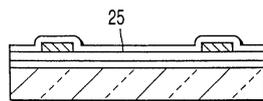
14a



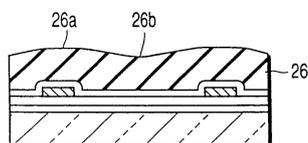
14b



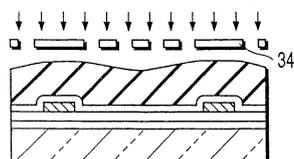
14c



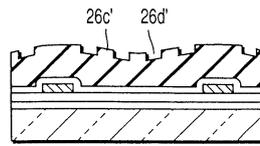
14d



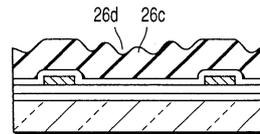
14e



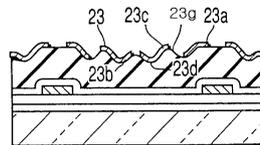
14f



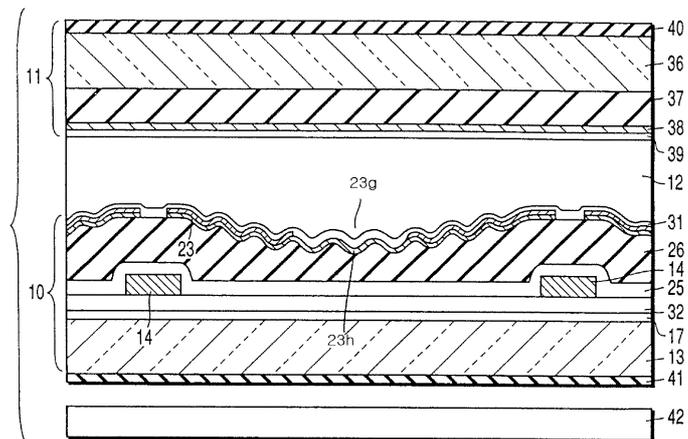
14g



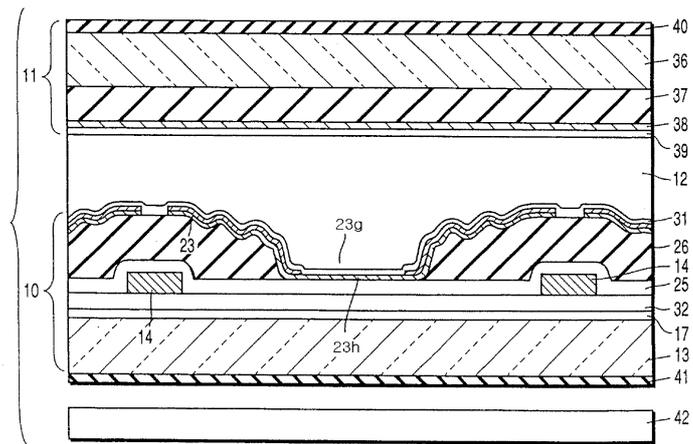
14h



15



16



专利名称(译)	液晶显示器		
公开(公告)号	KR1020020033574A	公开(公告)日	2002-05-07
申请号	KR1020010067168	申请日	2001-10-30
[标]申请(专利权)人(译)	株式会社东芝		
申请(专利权)人(译)	Sikki东芝股份有限公司		
当前申请(专利权)人(译)	Sikki东芝股份有限公司		
[标]发明人	NAGAYAMA KOHEI 나가야마고헤이 HANAZAWA YASUYUKI 하나자와야스유키		
发明人	나가야마고헤이 하나자와야스유키		
IPC分类号	G02F1/1362 G02F1/1333 G02B5/08 G02B5/02 G02F1/1335		
CPC分类号	G02F1/133553 G02F1/136227		
代理人(译)	KIM , YOON BAE		
优先权	2000333722 2000-10-31 JP 2001110450 2001-04-09 JP		
其他公开文献	KR100474058B1		
外部链接	Espacenet		

摘要(译)

本发明的液晶显示装置包括阵列基板，对置基板，夹在阵列基板和对置基板之间的液晶层，液晶层被分成多个像素区域，每个像素区域由阵列基板和对置基板控制那里。阵列基板包括对向基板和反射像素电极，反射像素电极通过液晶层散射入射光。反射像素电极具有用于在每个像素区域中设置平缓斜面（浮雕表面）的第一起伏（浮雕）和用于在每个像素区域中布置用作主散射部分的多个突起的第二浮雕并具有反光表面。

1 - 1 -

